10/707,878 FIS920030317US1

## In the United States Patent and Trademark Office

Date:

**HEREWITH** 

In re

Ashima Chakravarti, et al.

Filed:

1/20/04

Application of:

For:

Polycrystalline Silicon Layer With Nano-Grain

Structure And Method of Manufacture

Serial Number:

10/707,878

Confirmation No.

1877

Art Unit:

2891

Examiner:

SMITH, BRADLEY

## **AMENDMENT AFTER FINAL REJECTION**

Hon. Commissioner of Patents and Trademarks P. O. Box 1450 Alexandria, VA 23313-1450

Dear Sir:

In response to the Office Action mailed October 27, 2006, the present application is amended as follows: